

JC872 U.S. PTO  
09/892481  
06/28/01



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )  
Hisataka HAYASHI et al. )  
Serial No.: Not yet assigned ) Group Art Unit: Not assigned  
Filed: June 28, 2001 ) Examiner: Not assigned

For: PLASMA PROCESSING APPARATUS WITH REDUCED PARASITIC  
CAPACITY AND LOSS IN RF POWER

**Assistant Commissioner for Patents  
Washington, DC 20231**

Sir:

**INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. § 1.97(b)**

Pursuant to 37 C.F.R. §§ 1.56 and 1.97(b), applicants bring to the  
Examiner's attention the document listed on attached Form PTO-1449. A copy of  
the listed document is attached. Applicants respectfully request that the Examiner  
consider the document listed on attached Form PTO-1449 and indicate that it was  
considered by making an appropriate notation on this form.

This Information Disclosure Statement is being filed with the above-  
referenced application.

The following is a concise statement of relevance of the non-English  
language documents:

1. Japanese Patent Application No. 11-251302 discloses plasma  
etching method using dual frequency rf's.

An English-language abstract of the document is also enclosed.

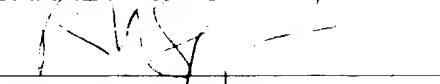
This submission does not represent that a search has been made or that no better art exists and does not constitute an admission that the listed document is material or constitutes "prior art." If the Examiner applies the document as prior art against any claim in the application and applicant determine that the cited document does not constitute "prior art" under United States law, applicants reserve the right to present to the office the relevant facts and law regarding the appropriate status of such document.

Applicants further reserve the right to take appropriate action to establish the patentability of the disclosed invention over the listed document, should one or more of the document be applied against the claims of the present application.

If there is any fee due in connection with the filing of this Statement, please charge the fee to our Deposit Account No. 06-0916.

Respectfully submitted,  
FINNEGAN, HENDERSON, FARABOW,  
GARRETT & DUNNER, L.L.P.

By:

  
Richard V. Burgujian  
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Dated: June 28, 2001

Enclosures  
RVB/FPD/dvz

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## INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Atty. Docket No. 03180.0282		Serial No.	Not Yet Assigned		
Applicant Hisataka HAYASHI et al.					
Filing Date	June 28, 2001		Group		
<b>U.S. PATENT DOCUMENTS</b>					
Examiner Initial*		Document Number	Date	Name	Class
					Sub Class
					Filing Date If Appropriate
<b>FOREIGN PATENT DOCUMENTS</b>					
		Document Number	Date	Country	Class
		11-251302	9/17/99	Japan	Sub Class
					Translation Yes or No
					Abstract
<b>OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)</b>					
Examiner		Date Considered			
*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.					
Form PTO 1449		Patent and Trademark Office - U.S. Department of Commerce			